

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT APPLICATION OF

Inventor(s): HASEGAWA et al.

Filed: Herewith

Title: METHOD OF PURGING CVD APPARATUS AND METHOD FOR JUDGING
MAINTENANCE OF TIMES OF SEMICONDUCTOR PRODUCTION APPARATUS

December 19, 2001

PRELIMINARY AMENDMENT

Hon. Commissioner of Patents
Washington, D.C. 20231

Sir:

Please amend this application as follows:

IN THE SPECIFICATION:

At the top of the first page, just under the title, insert:

1. ☒--This is a ☐ Continuation-In-Part ☒ Divisional
☐ Continuation ☐ Substitute Application (MPEP 201.09) of
1(a) ☒ National Application No. 09/651,255 filed August 30, 2000.
1(b) ☐ International Application No. PCT/___/
filed ___ which designated the U.S.--
2. ☐--This application claims the benefit of U.S. Provisional Application No.
60/___, filed ___--

IN THE CLAIMS:

Please cancel claims 1 and 8-14 without prejudice.

Respectfully submitted,

PILLSBURY WINTHROP LLP
Intellectual Property Group

By: 

G. Lloyd Knight
Reg. No: 17698
Tel. No.: 703.905.2117
Fax No.: 703.903.2500

GLK/ded
1600 Tysons Boulevard
McLean, VA 22102
(703) 905-2000